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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re patent of:  
Saini et al.

Application Serial No.: 10/799,836

Filed: 03/12/2004

For: Compact Microcolumn for  
Automated Assembly

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Customer Number: 000027683

Issued Patent No.: 7,081,630

Issued: 07/25/2006

Docket Number: 34003.110

SUBMISSION OF DOCUMENTS UNDER 37 CFR 1.501

Commissioner For Patents  
PO Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

The undersigned herewith submits in the above-identified patent the references (including a copy of the non-patent literature and foreign patent documents) listed on the attached PTO-1449 form. These documents are pertinent and applicable to the patent and may have a bearing on the patentability thereof on the basis that the documents were cited in pending United States patent applications.

Respectfully submitted,

Dated: 3 AUGUST 2006  
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R115125.1

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I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, PO Box 1450, Alexandria, VA 22313-1450 on <u>8-3-06</u>  Gayle Conner
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In place of  
PTO-1449  
Form

U. S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICE

Complete if Known

**INFORMATION DISCLOSURE  
STATEMENT BY APPLICANT**

(use as many sheets as necessary)

Application Number	10/799,836 (USP 7,081,630)
Filing Date	03/12/2004 (Issued: 07/25/2006)
Applicant(s)	Saini et al.
Art Unit	2881
Examiner Name	Smith, Johnnie L.
Attorney Docket Number	34003.110

SHEET 1 OF 3

**U. S. PATENT DOCUMENTS**

Examiner's Initials	Cite No.	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document
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Examiner  
Signature

Date  
Considered

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include a copy of this form with next communication to applicant.

R115126.1

Customer No. 000027683

In place of PTO-1449 Form		U. S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		Complete if Known	
<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b> <i>(use as many sheets as necessary)</i>				Application Number	10/799,836 (USP 7,081,630)
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				Applicant(s)	Saini et al.
				Art Unit	2881
				Examiner Name	Smith, Johnnie L.
SHEET	2	OF	3	Attorney Docket Number	34003.110

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NON-PATENT LITERATURE DOCUMENTS		
Examiner's Initials	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article, title of the item, date, page(s), volume-issue number(s), publisher, city/country where published
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Examiner Signature		Date Considered	
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